Abstract

A substrate holder (1) for holding a substrate (7) during a treatment process, for example during a bonding process, lithography process, coating process or cleaning process, the substrate holder (1) having a separating area (4) for separating areas with different pressure levels that arise between the substrate holder (1) and the substrate (1) when holding the substrate (7), the separating area (4) having a sealing device (5, 5‘, 5’’, 5’’’) and a pin element (6) and/or a further pin element (6‘), wherein the pin element (6) and/or the further pin element (6’) and the sealing device (5, 5‘, 5’’, 5’’’) are designed in such a way that, to form a non-contact sealing area, the pin element (6) and/or the further pin element (6‘) prevents contact in the separating area (4) between the sealing device (5, 5’, 5’’’, 5’’’) and the substrate (1’) at least in sections when the substrate (1) is held.

[Fig. 2]